



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. . . . . 09/559,903  
Filing Date . . . . . April 26, 2000  
Inventor . . . . . Zhiping Yin et al.  
Assignee . . . . . Micron Technology, Inc.  
Group Art Unit . . . . . 2815  
Examiner . . . . . Eckert II, George C.  
Attorney's Docket No. . . . . MI22-1427  
Title: Circuitry and Gate Stacks Encompassing a Semiconductive Substrate, a Metal  
Silicide Layer and Inorganic Material Layer in Physical Contact with the Metal Silicide  
Layer

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

To: Mail Stop RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

From: Jennifer J. Taylor, Ph.D. (Tel. 509-624-4276; Fax 509-838-3424)  
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Dear Sir:

The Examiner's attention is directed to the references which are listed on  
the attached Form PTO-1449 and copies of which are attached.

Citation of these references is respectfully requested.

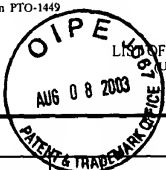
Respectfully submitted,

Dated:

*August 8, 2003*

By:

*Jennifer J. Taylor*  
Jennifer J. Taylor, Ph.D.  
Reg. No. 48,711

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1427	SERIAL NO. 09/559,903	
 LINES OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Zhiping Yin et al.		
				FILING DATE April 26, 2000	GROUP 2815	
U.S. PATENT DOCUMENTS						
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA 6,001,747	12-1999	Annasragada			
	AB					
	AC					
	AD					
	AE					
	AF					
	AG					
	AH					
	AI					
	AJ					
	AK					
	AL					
FOREIGN PATENT DOCUMENTS						
	Document Number	Date	Country	Class	Subclass	Translation
						Yes No
	AM					
	AN					
	AO					
	AP					
	AQ					
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)						
	AR	S. Wolf and R.N. Tauber, Silicon Processing for the VLSI Era (Vol 1-Process Technology), pages 189-190, 1986.				
	AS					
	AT					
EXAMINER				DATE CONSIDERED		
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.						

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